Special Issue

Recent Advances in Micro/Nanofabrication and Optical Devices

Message from the Guest Editor

We are pleased to announce a Special Issue on the "Recent Advances in Micro/Nanofabrication and Optical Devices" in our journal. Micro/nanofabrication has been rapidly advancing in recent years, driven by the demand for smaller and more efficient devices in various fields such as electronics, photonics, and biotechnology. The aim of this Special Issue is to present the recent advances in micro/nanofabrication and optical devices, including but not limited to novel micro/nanofabrication techniques, new optical devices, and emerging applications. The Special Issue will also explore the challenges and opportunities associated with the development of optical micro/nanofabrication and devices. Submissions should align with the scope of our journal and contribute to advancing the understanding of this field. We look forward to receiving your contributions and publishing a collection of high-quality articles that will advance the field of optical micro/nanofabrication and devices.

Guest Editor

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Deadline for manuscript submissions

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About the Journal

Message from the Editor-in-Chief

You are invited to contribute research articles or comprehensive reviews for consideration and publication in *Micromachines* (ISSN 2072-666X). *Micromachines* is published in the open access format. Research articles, reviews and other contents are released on the internet immediately after acceptance. The scientific community and the general public have unlimited free access to the content as soon as it is published. As an open access journal, *Micromachines* is supported by the authors or their institutes by payment of article processing charges (APC) for accepted papers. We are pleased to welcome you as our authors.

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